

**RESPONSE UNDER 37 CFR 1.116
EXPEDITED PROCEDURE
EXAMINING GROUP 1763**

**PATENT APPLICATION
Do. No. 5204-22**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of: Young Suk LEE; Young Mook KANG; Sang Do LEE

Serial No. 09/914,306

Examiner: Crowell, Anna M

Confirmation No. 2394

Filed: July 16, 2002

Group Art Unit: 1763

For: **PLASMA PROCESSING APPARATUS AND METHOD FOR
FORMING THIN FILMS USING THE SAME**

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT AFTER FINAL REJECTION UNDER 37 CFR 1.116

Responsive to the Office Action, dated July 7, 2003, please amend the application as follows.

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Argument begin on page 4 of this paper.